

## WEST Search History

DATE: Tuesday, May 20, 2003

### Set Name Query

side by side

### Hit Count Set Name

result set

*DB=USPT,PGPB,JPAB,EPAB,DWPI,TDBD; PLUR=YES; OP=ADJ*

L9	L8 and l6	5	L9
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L8	(clean\$3 or etch\$3 or treat\$4 or remov\$3) same (substrate or semiconductor or wafer) same ((ammonium fluoride) or 'NH.sub.4F')	1666	L8
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L7	L6 and l5	4	L7
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L6	((700/266  700/267  700/268  700/269  700/270  700/271  700/272  700/273  700/274 )!.CCLS.  (134/56R )!.CCLS.  (702/22  702/23  702/24  702/25  702/26  702/27  702/28  702/29  702/30  702/31  702/32 )!.CCLS.  (436/43  436/50  436/52  436/55  436/100  436/101  436/113  436/124  436/125 )!.CCLS.  (422/55  422/62  422/82.05  422/187  422/292 )!.CCLS. )	8326	L6
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L5	((clean\$3 or etch\$3 or treat\$4 or remov\$3) with (substrate or semiconductor or wafer)) same ((ammonium fluoride) or 'NH.sub.4F') with (water or ammonia or 'NH.sub.3')	1205	L5
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*DB=JPAB,EPAB,DWPI; PLUR=YES; OP=ADJ*

L4	2000150447	2	L4
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*DB=JPAB; PLUR=YES; OP=ADJ*

L3	JP2000150447	1	L3
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*DB=JPAB,EPAB,DWPI; PLUR=YES; OP=ADJ*

L2	JP2000150447	1	L2
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L1	Jp2000-150447	0	L1
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END OF SEARCH HISTORY

## Patent Assignment Abstract of Title

### Total Assignments: 1

**Application #:** 09905662 **Filing Dt:** 07/13/2001 **Patent #:** NONE **Issue Dt:**  
**PCT #:** NONE **Publication #:** 20020046757 **Pub Dt:** 04/25/2001  
**Inventors:** Yasuhito Inagaki, Mineo Shimizu, Yoshihiro Fujitani  
**Title:** Substrate cleaning method and substrate cleaning apparatus

### Assignment: 1

**Reel/Frame:** 012421/0513 **Received:** 01/09/2002 **Recorded:** 01/03/2002 **Mailed:** 02/26/2002 **Pages:**

**Conveyance:** ASSIGNMENT OF ASSIGNORS INTEREST (SEE DOCUMENT FOR DETAILS).

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**Exec Dt:** 10/19/2001  
**Exec Dt:** 10/22/2001  
**Exec Dt:** 10/23/2001

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Search Results as of: 5/20/2003 5:03:07 P.M.

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